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PELLICLE FILM THINNING TEST

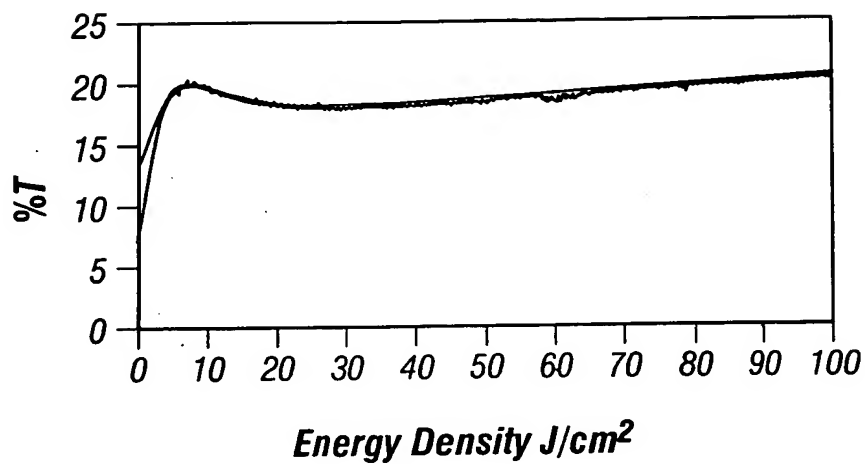


FIG. 1

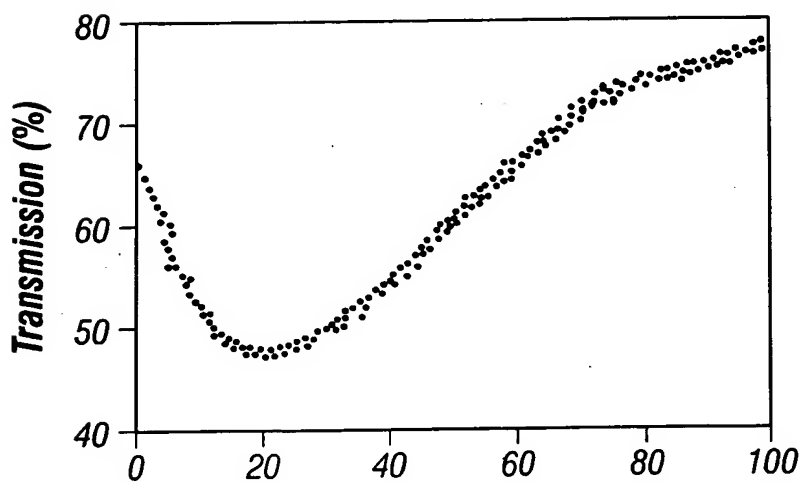


FIG. 2

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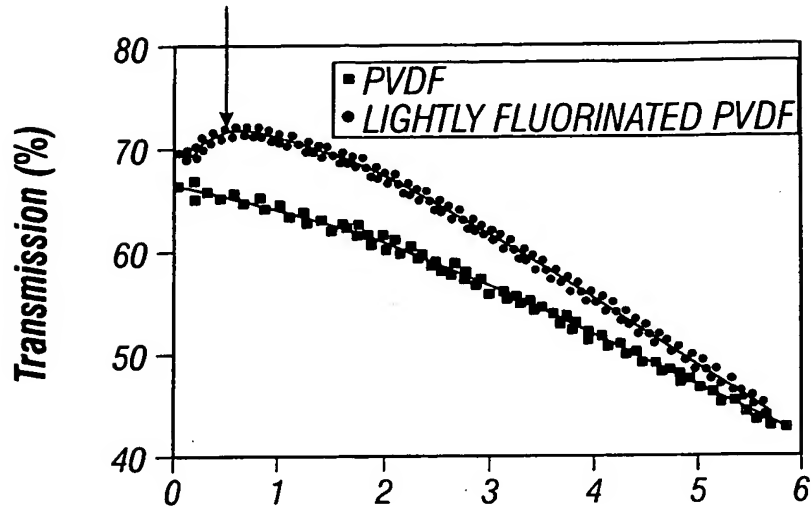


FIG. 3

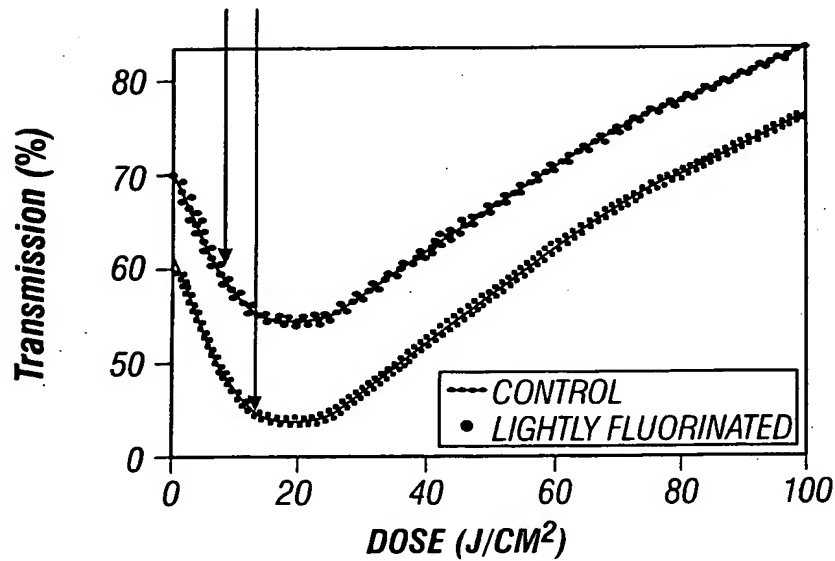


FIG. 4

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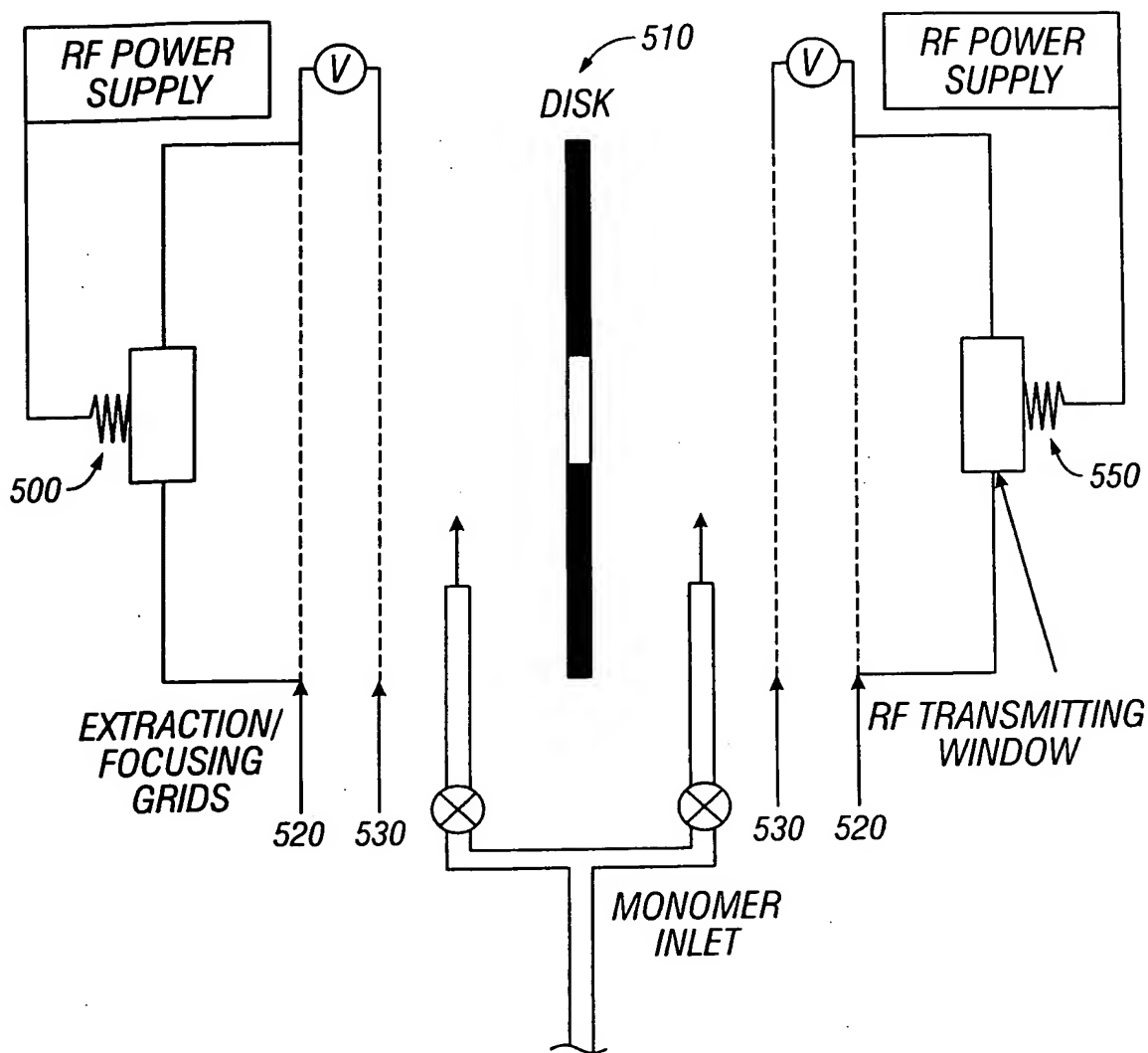


FIG. 5

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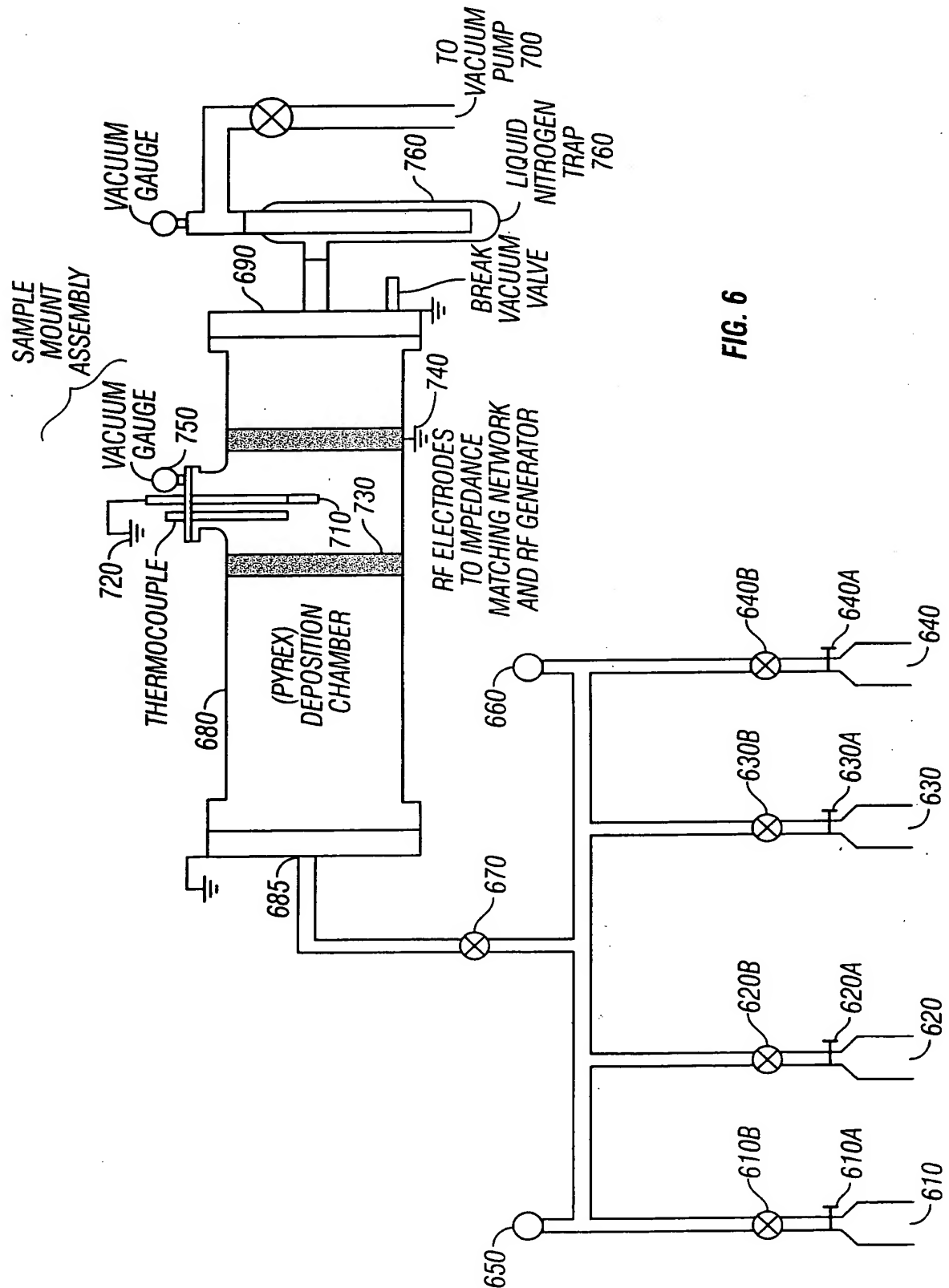




FIG. 7

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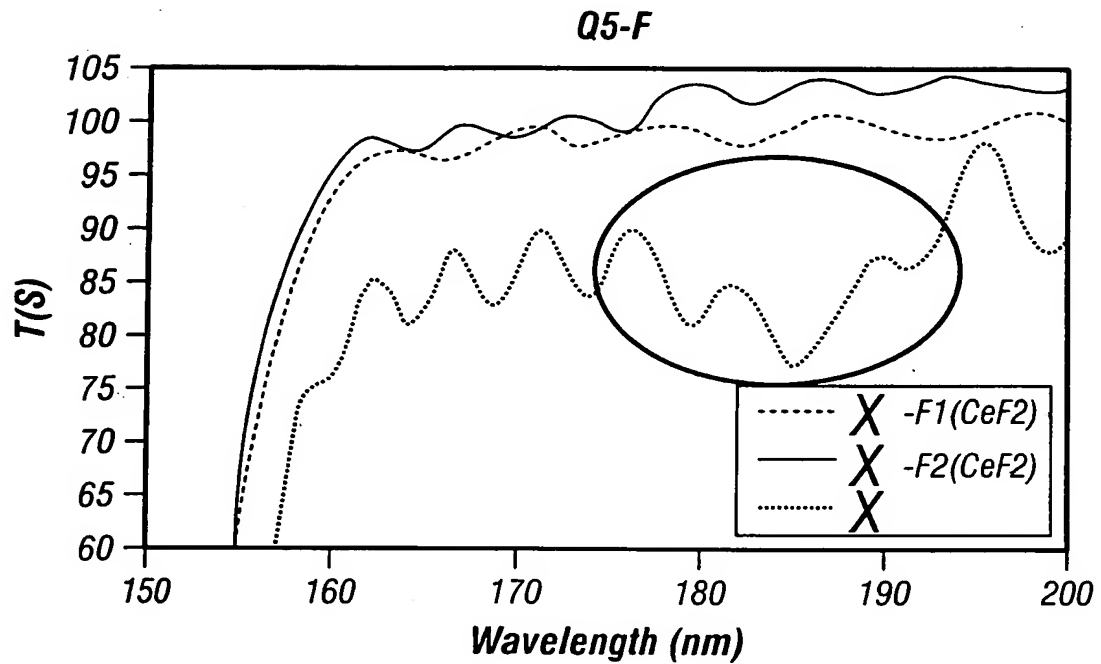


FIG. 8

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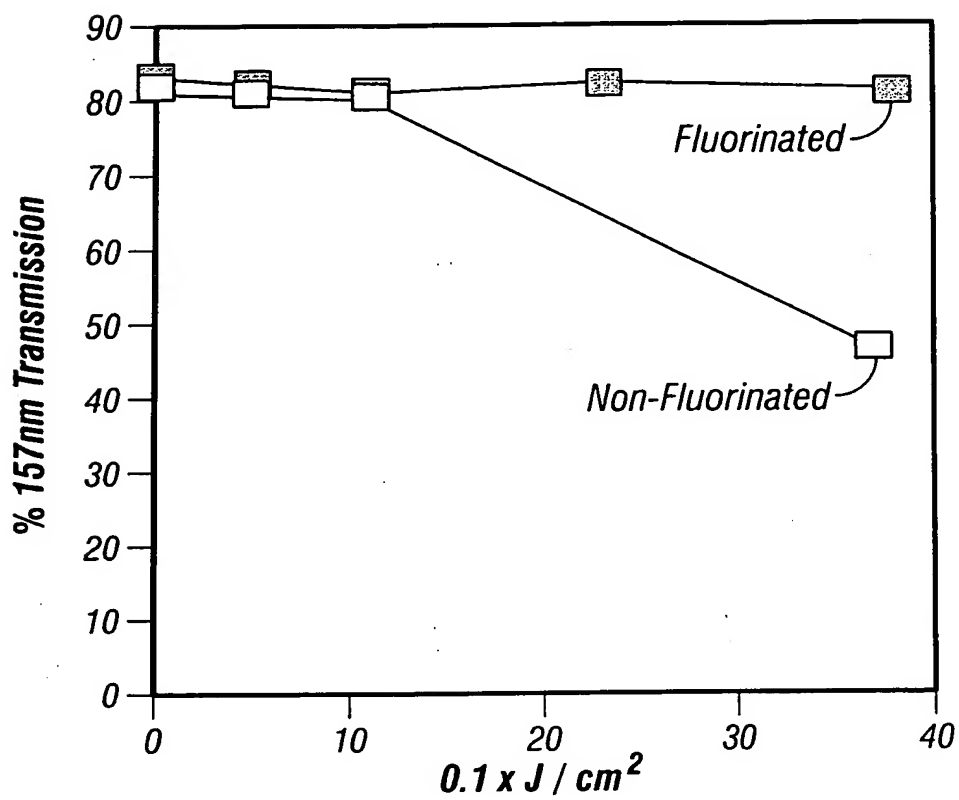
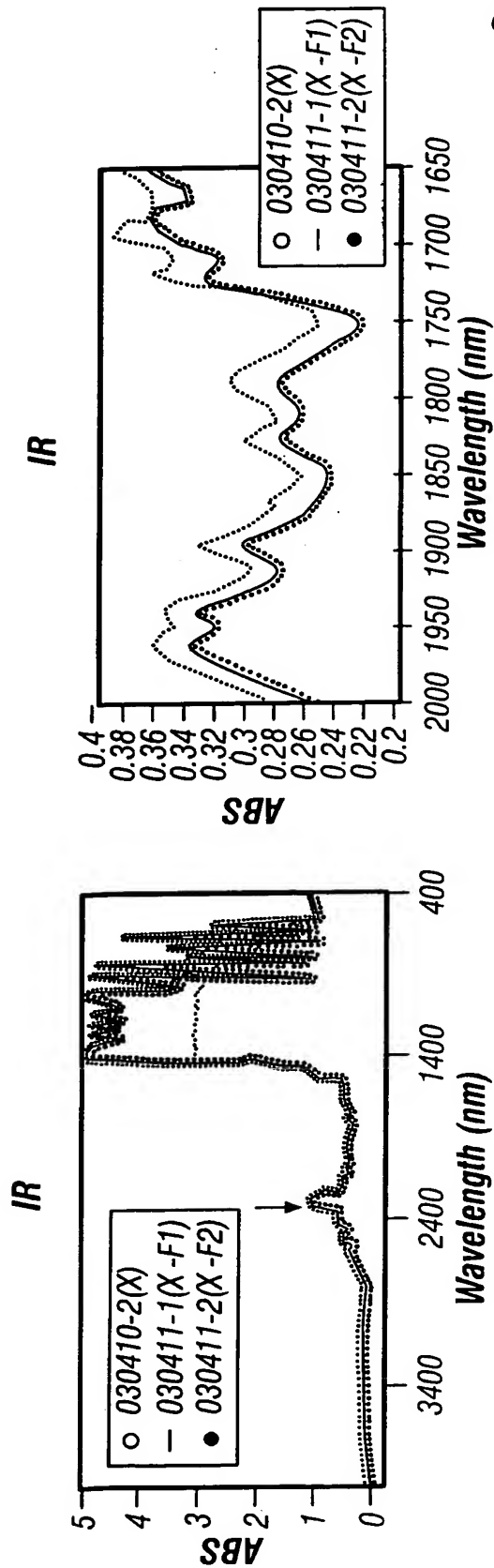


FIG. 9

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Peak Intensity Ratio (1790cm-1 vs 2290cm-1)

	X	X-F1	F-F2
Peak Intensity Ratio	0.488	0.414	0.409

FIG. 8